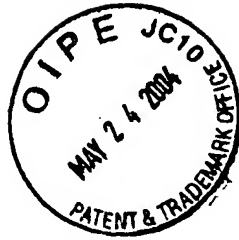


FILED
JUL 10 2004



PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:
Eugene P. Marsh

Serial No.: 10/634,362

Filed: August 8, 2003

For: **ATOMIC LAYER DEPOSITION OF
METAL DURING THE FORMATION OF A
SEMICONDUCTOR DEVICE**

§
§ Group Art Unit: 2812
§
§ Examiner: Lynne Ann Gurley
§
§ Atty. Docket: 2003-0659.00/US
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§
§
§
§

Commissioner for Patents
PO Box 1450
Alexandria, VA 22313-1450

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May 20, 2004
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Susan Jerome
Signature

RESPONSE TO THE OFFICE ACTION OF JANUARY 22, 2004

Please enter the following in response to the Examiner's office action mailed January 22, 2004 as paper no. 1203.